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PATENT  
Attorney Docket No. 04329.3304-00

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

|                             |   |                              |
|-----------------------------|---|------------------------------|
| In re Application of:       | ) |                              |
|                             | ) |                              |
| Ayako NAKANO et al.         | ) | Group Art Unit: 1795         |
|                             | ) |                              |
| Application No.: 10/823,539 | ) | Examiner: Stephen D. ROSASCO |
|                             | ) |                              |
| Filed: April 14, 2004       | ) |                              |
|                             | ) |                              |
| For: PATTERN FORMING METHOD | ) | Confirmation No.: 4440       |
| AND SYSTEM, AND METHOD OF   | ) |                              |
| MANUFACTURING A             | ) |                              |
| SEMICONDUCTOR DEVICE        | ) |                              |

**Mail Stop AF**  
 Commissioner for Patents  
 P.O. Box 1450  
 Alexandria, VA 22313-1450

Sir:

**INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(d)**

Pursuant to 37 C.F.R. §§ 1.56 and 1.97(d), Applicants bring to the attention of the Examiner the documents on the attached listing. This Information Disclosure Statement is being filed after a final Office Action and is accompanied by the required fee of \$180.00 as specified under § 1.17(p) and a certification as specified under § 1.97(e).

Each document listed in this Information Disclosure Statement was first cited in a communication from the Japanese Patent Office in a counterpart foreign application, and this Information Disclosure Statement is being filed within three months of the mailing date of that communication.

Copies of the listed foreign documents are enclosed. Applicants respectfully request that the Examiner consider the listed documents and indicate that they were considered by making appropriate notations on the attached form.

The documents were cited in a Notification of Reasons for Rejection from the Japanese Patent Office mailed on October 2, 2007 ("Notification"), in a counterpart foreign application. The Notification indicates the relevance of each of the listed non-English-language documents. The Notification and an English-language translation of the Notification are enclosed. Applicants do not necessarily endorse any conclusions set forth in the Notification. English-language Abstracts of the listed foreign publications are also enclosed for the Examiner's convenience.

This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that each or all of the listed documents are material or constitute "prior art." If the Examiner applies any of the documents as prior art against any claims in the application and Applicants determine that the cited documents do not constitute "prior art" under United States law, Applicants reserve the right to present to the office the relevant facts and law regarding the appropriate status of such documents.

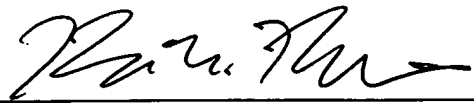
Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the listed documents, should one or more of the documents be applied against the claims of the present application.

If there is any fee due in connection with the filing of this Statement, please charge the fee to Deposit Account No. 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,  
GARRETT & DUNNER, L.L.P.

Dated: January 2, 2008

By: 

Reece Nienstadt  
Reg. No. 52,072